


Form PTO-1449 (REV. 1/06)		US Dept. of Commerce <b>PATENT &amp; TRADEMARK OFFICE</b>  INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)		ATTY DOCKET NO. 118039		APPLICATION NO. 10/733,454	
							
				APPLICANT(S) Shigemori OHTSU et al.			
				FILING DATE December 12, 2003		GROUP 1791	

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name
	1	6,901,198	5/2005	Shimizu et al.
	2	4,884,434	12/1989	Satake et al.
	3	5,716,556	2/1998	Heard
	4	5,949,945	9/1999	Okano et al.
	5	6,314,228	11/2001	Korenaga et al.
	6	6,355,198	3/2002	Kim et al.
	7	2002/0114556	8/2002	Kato et al.
	8	7,174,057	2/2007	Shimizu et al.
	9	5,999,670	10/2005	Yoshimura et al.
	10	5,999,670	10/2005	Furuyama
	10	2005/0238278	10/2005	Nakashiba et al.

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	12	JP A 08-160239 (now Japanese Patent No. 3151364)	1/2001	Japan	X	X
	13	JP A 10-300961	11/1998	Japan	X	X
	14	JP A 2000-039530	2/2000	Japan	X	X
	15	JP A 2000-039531	2/2000	Japan	X	X
	16	JP A 2000-235127	8/2000	Japan	X	X
	17	JP A 2002-333538	11/2002	Japan	X	X
	18	JP A 2004-029507	1/2004	Japan	X	X
	19	JP A 2004-086144	3/2004	Japan	X	X
	20	JP A 2004-109927	4/2004	Japan	X	X

OTHER DOCUMENTS		
Examiner Initials	Cite No.	Including name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
	21	Whitesides et al., "The Art of Building Small," Scientific American, pp. 39-47, September 2001.
	22	Xia et al., "Soft Lithography," Annu. Rev. Mater. Sci., pp. 153-184, 1998.

EXAMINER	DATE CONSIDERED
----------	-----------------

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: September 6, 2008

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /M.V./

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118039		APPLICATION NO. 10/733,454	
INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)				APPLICANT(S) Shigemi OHTSU et al.			
				FILING DATE December 12, 2003		GROUP 1791	
U.S. PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Date	Name			
	23	7,317,861	8/2008	Ohtsu et al.			
	24	7,294,292	11/2007	Akutsu et al.			
	25	6,500,603	12/2002	Shioda			
	26	2005/0133943	6/2005	Akutsu et al.			
	27	10/801,803	3/2004	Akutsu et al.			
	28	6,243,517	6/2001	Deacon			
	29	2005/0163446	7/2005	Shimizu et al.			
FOREIGN PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation	
	30	JP A 05-066435	3/1993	Japan	X	X	
	31	JP A 2002-311273	10/2002	Japan	X	X	
	32	JP A 02-155704	6/1990	Japan	X		
	33	JP A 06-114845	4/1994	Japan	X	X	
	34	JP A 06-304933	11/1994	Japan	X	X	
	35	JP A 08-507800	8/1996	Japan	X		
	36	JP A 09-269429	10/1997	Japan	X	X	
	37	JP A 2003-084157	3/2003	Japan	X	X	
OTHER DOCUMENTS							
Examiner Initials	Cite No.	Including name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
	38	B. Michel et al., "Printing Meets Lithography: Soft Approaches to High-Resolution Patterning," IBM J. Res. & Dev., vol. 45, No. 5, pp. 697-719, Sep. 2001.					
EXAMINER					DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118039		APPLICATION NO. 10/733,454	
INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)				APPLICANT(S) Shigemitsu OHTSU et al.		FILING DATE December 12, 2003	
				GROUP 1791			
U.S. PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Date	Name			
FOREIGN PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation	
	39	JP A 10-090532	4/1998	Japan	X	X	
	40	JP A 10-130323	5/1998	Japan	X	X	
	41	JP A 11-003545	1/1999	Japan	X	X	
	42	JP A 2001-269958	10/2001	Japan	X	X	
	43	JP A 2002-086462	3/2002	Japan	X	X	
	44	JP A 2002-086515	3/2002	Japan	X	X	
	45	JP A 2002-088120	3/2002	Japan	X	X	
	46	JP A 2002-090565	3/2002	Japan	X	X	
	47	JP A 2002-284812	10/2002	Japan	X	X	
OTHER DOCUMENTS							
Examiner Initials	Cite No.	Including name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
	49	Xiao-Mei Zhao et al., "Fabrication of Single-Mode Polymeric Waveguides Using Micromolding in Capillaries", Advanced Materials, vol. 8, No. 5, pp. 420-424, May 1996.					
	49	R. Hsu et al., "Formation of Micro-Sized Cycloolefin Copolymer from Toluene Solution Using Compressed HFC-134a As Antisolvent", Applied Polymer Science, vol. 84, No. 9, pp. 1657-1668.					
	52	Y. Wada, "Function & Materials", vol. 20, No. 8, pp. 16-22, August 2000.					
	52	H. Shinohara, "Chemistry & Economy", vol. 44, No. 14, pp. 74-82, December 1997.					
	52	Y. Wada, "Function & Materials", vol. 13, No. 1, pp. 40-52, January 1993.					
EXAMINER  Mathieu Vargot/				DATE CONSIDERED 10/26/2008			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							